



MIT.9996

IFW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANT: Gil et al.

GROUP: 2881

SERIAL NO: 10/677,173

EXAMINER: Unknown

FILED: 10/02/2003

FOR: SYSTEM AND METHOD FOR FABRICATION AND REPLICATION OF
DIFFRACTIVE OPTICAL ELEMENTS FOR MASKLESS
LITHOGRAPHY

Mail Stop DD
Commissioner of Patents
P.O. Box 1450
Alexandria, VA 22313-1450
Sir:

INFORMATION DISCLOSURE STATEMENT

In compliance with 37 C.F.R. §§1.56, 1.97, and 1.98, Applicant submits copies of the documents listed on the attached Form PTO-1449.

The listed documents were recently cited in a corresponding PCT application, and a copy of the Communication is being submitted herewith for purposes of convenience.

The Commissioner is authorized to charge Deposit Order Account No. 19-0079 for any further fee that is required.

Respectfully submitted,

Matthew E. Connors
Registration No. 33,298
Gauthier & Connors, LLP
225 Franklin Street, Suite 3300
Boston, Massachusetts 02110
Telephone: (617) 426-9180
Extension: 112

I hereby certify that this paper (along with any paper referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to the Mail Stop DD, Commissioner of Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

Emily C. Porell

08/30/2004
Date

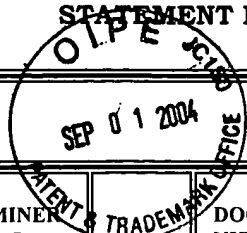
FORM PTO-1449
(Rev. 5/92)GAUTHIER & CONNORS LLP
225 Franklin Street, Boston, MA 02110
Telephone: (617) 426-9180MIT.9996
ATTORNEY DOCKET NO.

APPLICANT: Gil et al.

FILING DATE: 10/02/200310/677,173
SERIAL NO.

GROUP: 2881

EXAMINER: Unknown

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT****U.S. PATENT DOCUMENTS**

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	AA	200/0019305	02/14/2002	Wu			08/21/2001
	AB	5,900,637	05/04/1999	Smith			05/30/1997
	AC	5,549,934	08/27/1996	Garza et al.			06/05/1995
	AD	6,410,213	06/25/2002	Raguin et al.			06/09/1998
	AE						
	AF						
	AG						
	AH						
	AI						

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES NO
	AJ						
	AK						
	AL						

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

EXAMINER INITIAL		
	AM	"Hydrogen silsesquioxane/novolac bilayer resist for high aspect ratio nanoscale electron-beam lithography," Falco et al. <i>J. Vac. Sci. Technol. B.</i> , Nov./Dec. 2000.
	AN	"Low energy lithography; energy control and variable energy exposure," Brunger et al. <i>Microelectric Engineering</i> . 1995. Vol. 27.
	AO	

EXAMINER

DATE CONSIDERED

EXAMINER:

Initial if citation considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.